

ASTM 10780339 MEM cantilever with dielectric layer thicker than conductive layer

- ↳ S29:(101).mln."
- ↳ S30:(130) Backward citation search 2
- ↳ S31:(23996918) thick\$4 thin\$4
- ↳ S32:(18167572) thick\$4 thin\$4
- ↳ S32:(124201121) conduct\$4
- ↳ S34:(125295560) S12 S33
- ↳ S35:(14880011) S14 with S34
- ↳ S36:(1772681) S35 with S32
- ↳ S37:(110) S23 and S36
- ↳ S38:(148) S21 and S36
- ↳ S39:(109121) S36.clm.
- ↳ S40:(1) S21 and S39
- ↳ S41:(593) S18 adj2 88
- ↳ S42:(151) S41 and S39
- ↳ S43:(141) S41 same S36
- ↳ S44:(1301) S8 same S36
- ↳ S45:(12263424) thick\$4
- ↳ S46:(1605081) S14 near6 S45
- ↳ S47:(1078001) S34 near6 S45
- ↳ S48:(171) S44 and S48
- ↳ S49:(151) S48 and S47
- ↳ S50:(1281) S49 and S22
- ↳ S51:(272701312) with S14
- ↳ S52:(1101) S23 S53
- ↳ S53:(141) S32 and S31

49 and 48

May 2005

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U	Inventor	Document	Issue P	Title	Current	Current X	Review	S	C	P	Y	Image	Op
1	<input type="checkbox"/> <input checked="" type="checkbox"/> Kemoda; Te	US 659032	2003	H	Field emission electron source	313/31	313/498	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
2	<input type="checkbox"/> <input checked="" type="checkbox"/> Busta; Hein	US 6140646	2000	21	Direct View infrared MEMS structure	250/23	250/338.1	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6140646
3	<input type="checkbox"/> <input checked="" type="checkbox"/> Bartha; Jóh	US 5116482	1992	H	Method of producing micromechanicals	216/2	216/71	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	
4	<input type="checkbox"/> <input checked="" type="checkbox"/> Bernstein; J	US 4705659	1987	H	Carbon film addition for free-standin	264/29	216/12	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	

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